

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 12732-061002	Application No. 10/792,132
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Taketomi Asami et al.	
		Filing Date March 4, 2004	Group Art Unit

## U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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	AB	2002/0014625 A1	02/07/2002	Asami et al.			
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Examiner Signature <b>JOSEPH NGUYEN</b>	Date Considered <b>11/09/05</b>
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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	ABB	6,690,068	02/10/2004	Yamazaki et al.			

### Foreign Patent Documents or Published Foreign Patent Applications

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							Yes	No
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JN	AKK	R. Ishihara et al.; "Microtexture Analysis of Location Controlled Large Si Grain Formed by Excimer-Laser Crystallization Method"; <u>Active-Matrix Liquid-Crystal Displays 1999</u> ; TFT Technologies and Related Materials; Digest of Technical Papers; Kogakuin University, Tokyo, Japan; July 14-16, 1999, pp. 99-102.
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